

WHAT IS CLAIMED IS:

1. A profile measuring method of calculating,
using a phase shift method, a phase value of
an interference image formed by a light beam reflected
5 from an object and a light beam reflected from
a reference mirror, thereby obtaining an optical
path difference from the calculated phase value and
obtaining a profile of the object from the optical path
difference, comprising:

10 emitting, to the object, two flash light beams,
having wavelengths slightly different from each other,
with a predetermined interval t_1 therebetween; and
picking up, using a camera, interference light
formed by light beams reflected from the object and
15 a light beam reflected from the reference mirror, while
moving the object in a direction, in which the two
flash light beams are directed, in units of intervals
 t_2 at which each of the two flash light beams is
cyclically emitted, a phase shift amount corresponding
20 to a movement amount of the object at a time being set
to a value falling within a range of $2n\pi \pm \pi/2 \pm \pi/4$.

2. A profile measuring method according to
claim 1, wherein the two flash light beams are light
beams of predetermined wavelengths obtained by passing
25 white light emitted from flash lamps through band-pass
filters.

3. A profile measuring method according to

- claim 1, wherein the camera has a high-speed double exposure function.

4. A profile measurement apparatus comprising:

a first flash light source which emits a flash
5 light beam of a first wavelength;
a second flash light source which emits a flash
light beam of a second wavelength, different from the
first wavelength, with an interval t_1 from the light
beam of the first wavelength;

10 a movement table which moves an object in
a direction in which the flash light beams from the
first and second flash light sources are directed to
the object;

a translucent mirror which diverges, to
15 a reference mirror, part of the two flash light beams
emitted from the first and second flash light sources
and directed to the object, the translucent mirror
returning, to an original route, light reflected from
the reference mirror;

20 a camera which picks up, as an image, interference
light formed by light reflected from the object and
light reflected from the reference mirror;

a table control section which moves the movement
table by a predetermined distance in synchronism with
25 an interval t_2 between successive emissions of light
from the first and second flash light sources; and
an image processing unit which selects an image

signal with a maximum amplitude from a plurality of
images output from the camera when the movement table
has been moved by the predetermined distance in
synchronism with the interval t_2 , thereby determining
5 an optical path difference on the basis of a phase
difference between two interference images created by
the two flash light beams emitted from the first and
second flash light sources when the camera has picked
up the image signal with the maximum amplitude, and
10 also on the basis of phase values of the interference
images assumed when the camera has picked up the image
signal with the maximum amplitude.

5. A profile measurement apparatus according to
claim 4, wherein the first and second flash light
15 sources emit light beams of predetermined wavelengths
obtained by passing white light emitted from flash
lamps through band-pass filters.

6. A profile measurement apparatus according to
claim 4, wherein the camera has a high-speed double
20 exposure function for individually picking up two
interference images formed by two light beams of
different wavelengths emitted with a slight interval of
1 msec. at maximum, preferably, 200 nsec. to
50 microsec., and more preferably, 10 microsec.

25 7. A profile measurement apparatus according to
claim 4, wherein the movement table is moved in
synchronism with the interval t_2 between successive

emissions of light from the first and second flash light sources, in a direction in which the two flash light beams are directed, such that the movement table can provide a phase shift amount falling within a range of $2n\pi \pm \pi/2 \pm \pi/4$, n being an integer not less than 1.

8. A profile measurement apparatus comprising:
- a first flash light source which emits a flash light beam of a first wavelength;
 - a second flash light source which emits a flash light beam of a second wavelength, different from the first wavelength, with an interval t_1 from the light beam of the first wavelength;
 - a movement table which moves an object in a direction in which the flash light beams from the first and second flash light sources are directed to the object;
 - a translucent mirror which diverges, to a reference mirror, part of the two flash light beams emitted from the first and second flash light sources and directed to the object, the translucent mirror returning, to an original optical path, light reflected from the reference mirror;
 - a camera which picks up, as an image, interference light formed by light reflected from the object and light reflected from the reference mirror;
 - a table control section which moves the movement table by a predetermined distance in synchronism with

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- an interval t_2 between successive emissions of light from the first and second flash light sources; and

an image processing unit which selects an image with a maximum amplitude from a plurality of images output from the camera each time the first and second flash light sources emit their respective light beams with the interval t_1 interposed therebetween, and also each time the movement table is moved by the predetermined distance in synchronism with the interval t_2 , the image processing unit then calculating an optical path difference from two interference images formed by the two light beams emitted from the first and second flash light sources and reflected from a surface of the object, the image processing unit calculating respective optical path differences at the points, thereby determining a surface profile of the object on the basis of phase values of the two flash light beams emitted from the first and second flash light sources when the camera has picked up an image signal with a maximum amplitude from the output images at each of the points of the to-be-measured area of the object.

9. A profile measurement apparatus according to claim 8, wherein the first and second flash light sources emit light beams of predetermined wavelengths obtained by passing white light emitted from flash lamps through band-pass filters.

10. A profile measurement apparatus according to claim 8, wherein the camera has a high-speed double exposure function for individually picking up two interference images formed by two light beams of different wavelengths emitted with a slight interval of 1 msec. at maximum, preferably, 200 nsec. to 50 microsec., and more preferably, 10 microsec.

11. A profile measurement apparatus according to claim 8, wherein the movement table is moved in synchronism with the interval t_2 between successive emissions of light from the first and second flash light sources, in a direction in which the two flash light beams are directed, such that the movement table can provide a phase shift amount falling within a range of $2n\pi \pm \pi/2 \pm \pi/4$, n being an integer not less than 1.